

Accepted Manuscript

Title: The effect of formic acid concentration on the conductivity and corrosion resistance of chromium carbide coatings electroplated with trivalent chromium

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PII: S0169-4332(13)01107-0
DOI: <http://dx.doi.org/doi:10.1016/j.apsusc.2013.06.008>
Reference: APSUSC 25811

To appear in: *APSUSC*

Received date: 1-3-2013
Revised date: 5-5-2013
Accepted date: 2-6-2013

Please cite this article as: C.-E. Lu, N.-W. Pu, K.-H. Hou, C.-C. Tseng, M.-D. Ger, The effect of formic acid concentration on the conductivity and corrosion resistance of chromium carbide coatings electroplated with trivalent chromium, *Applied Surface Science* (2013), <http://dx.doi.org/10.1016/j.apsusc.2013.06.008>

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The effect of formic acid concentration on the conductivity and corrosion resistance of chromium carbide coatings electroplated with trivalent chromium

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